

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

priority Application Serial No.09/943,186
Confirmation No.unknown
priority Filing DateAugust 29, 2001
Inventor..... John F. Van Itallie et al.
Assignee..... Micron Technology, Inc.
Group Art Unit.....unknown
Examinerunknown
Attorney's Docket No.MI22-2458
Customer No.021567
Title: Photolithographic Methods Of Using A Single Reticle To Form Overlapping Patterns

PRELIMINARY AMENDMENT

To: Mail Stop Patent Application
Commissioner for Patents
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AMENDMENTS